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APPLICATION NO. FILIN		ING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/784,171	784,171 02/16/2001		Norio Kimura	2001-0163A	1530
513	7590	08/23/2002			
		D & PONACK, I	EXAMINER		
2033 K STR SUITE 800			ROSE, ROBERT A		
WASHINGTON, DC 20006-1021				ART UNIT	PAPER NUMBER
				3723	
				DATE MAILED: 08/23/2002	DATE MAILED: 08/23/2002

Please find below and/or attached an Office communication concerning this application or proceeding.



Applicant(s)

Office Action Summary

09/784,171

Kimura et al

Examiner

Application No.

Robert Rose

Art Unit 3723



	The MAILING DATE of this communication appears of	n the cover sheet with the correspondence address					
	for Reply						
THE N	A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.136 (a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the						
	ions of time may be available under the provisions of 37 CFR 1.136 (a). In r date of this communication.	o event, however, may a reply be timely filed after SIX (6) MONTHS from the					
- If NO p - Failure - Any re	period for reply specified above is less than thirty (30) days, a reply within the period for reply is specified above, the maximum statutory period will apply and to reply within the set or extended period for reply will, by statute, cause the ply received by the Office later than three months after the mailing date of the patent term adjustment. See 37 CFR 1.704(b).	d will expire SIX (6) MONTHS from the mailing date of this communication. explication to become ABANDONED (35 U.S.C. § 133).					
Status		,					
1) 💢	Responsive to communication(s) filed on Apr 25, 20						
2a) 🗆	This action is FINAL . 2b) 💢 This acti	on is non-final.					
3) 🗆	Since this application is in condition for allowance e closed in accordance with the practice under Ex par	xcept for formal matters, prosecution as to the merits is te Quayle, 1935 C.D. 11; 453 O.G. 213.					
Disposi	tion of Claims						
4) 💢	Claim(s) <u>1-6</u>	is/are pending in the application.					
4	la) Of the above, claim(s)	is/are withdrawn from consideration.					
5) 🗆	Claim(s)	is/are allowed.					
6) 💢	Claim(s) 1-6	is/are rejected.					
7) 🗆	Claim(s)	is/are objected to.					
8) 🗆	Claims	are subject to restriction and/or election requirement.					
Applica	ition Papers	•					
9) 🗆	The specification is objected to by the Examiner.						
10)	The drawing(s) filed on is/are	a) accepted or b) objected to by the Examiner.					
	Applicant may not request that any objection to the di	awing(s) be held in abeyance. See 37 CFR 1.85(a).					
11)	The proposed drawing correction filed on	is: a) \square approved b) \square disapproved by the Examiner.					
	If approved, corrected drawings are required in reply t	o this Office action.					
12)	The oath or declaration is objected to by the Exami	ner.					
Priority	under 35 U.S.C. §§ 119 and 120						
13)💢	Acknowledgement is made of a claim for foreign pr	iority under 35 U.S.C. § 119(a)-(d) or (f).					
a) 🕽	(i All b)□ Some* c)□ None of:	·					
	1. X Certified copies of the priority documents have	e been received.					
	2. Certified copies of the priority documents have	e been received in Application No					
	application from the International Burea						
_	ee the attached detailed Office action for a list of the						
. –	Acknowledgement is made of a claim for domestic						
a)∟ 15\□	The translation of the foreign language provisiona Acknowledgement is made of a claim for domestic						
Attachm		priority ander 55 0.5.6. 33 120 and/or 121.					
	otics of References Cited (PTO-892)	4) Interview Summary (PTO-413) Paper No(s).					
2) No	otice of Draftsperson's Patent Drawing Review (PTO-948)	5) Notice of Informal Patent Application (PTO-152)					
3) M Information Disclosure Statement(s) (PTO-1449) Paper No(s). 3 6) Other:							

Application/Control Number: 09/784171 Page 2

Art Unit: 3723

DETAILED ACTION

- 1. Receipt is acknowledged of Applicant's Prior Art Statement, filed April 25, 2001.
- 2. Receipt is acknowledged of Applicant's Foreign Priority Papers, filed April 25, 2001.
- 3. Claims 1-6 are presented for examination.
- 4. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless --

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 5. Claim 6 is rejected under 35 U.S.C. 102(b) as being clearly anticipated by Takahashi et al(US 5672091). Takahashi et al disclose a polishing apparatus comprising all of the subject matter set forth in applicant's claim. Note optical endpoint detection device (3)(4) adjacent polishing table(1) for detecting the state of the wafer(F) held by top ring(2), without removal of the wafer from the table.
- 6. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 7. Claims 1-5 are rejected under 35 U.S.C. 103(a) as being unpatentable over Takahashi in view of Stephan(Australian No. 245213). Takahashi et al discloses an optical endpoint detection

Application/Control Number: 09/784171

Art Unit: 3723

device for a cmp machine comprising an optical measuring device located adjacent an outer edge

Page 3

of the polishing pad to detect the surface of an overhanging wafer. While the polishing table

lacks a notch in it's outer surface to allow light to pass through for observation of the work, such

structure is known in the optical detection art as evidenced by Stephan. To provide one or more

such notches in the outer periphery of the polishing table in Takahashi et al to locate the optical

endpoint detection device as close as possible to the polishing table to save space, while still

allowing detection of the state of the workpiece without removal of the workpiece would have

been obvious in view of Stephan.

8. The prior art made of record and not relied upon is considered pertinent to applicant's

disclosure. Lenkersdorfer and Lebel et al are cited to show optical endpoint detectors for cmp

having rinsing fluid nozzles in proximity to the optical measuring device. Holzapfel et al is cited

to show another optical measuring device located at the edge of the polishing pad and having an

associated probe cleaning nozzle. Japan No. 403234467 is cited to show an optical measurement

device comprising a window incorporated into the polishing table for detecting the state of the

work surface during polishing. Mayama is cited to show another rotary polishing tool having

optical detection notches in it's periphery.

9. Any inquiry concerning this communication should be directed to Robert Rose at

telephone number (703) 308-1360.

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August 20, 2002.

ROBERT A. ROSE PRIMARY EXAMINER ART UNIT 323